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APPLICANTS										
Kenji Tokunaga, Hachioji, JAPAN;										
MONE MDH 10/26/04										
** FOREIGN APPLICATIONS ************************************										
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/07/2004										
Foreign Priority claimed	STATE OR	SHE	SHEETS TOT		AL	INDEPENDENT				
1 (T						WING 21	CLAIMS 14		CLAIMS 3	
ADDRESS 020457 ANTONELLI, TERRY, STOUT & KRAUS, LLP 1300 NORTH SEVENTEENTH STREET SUITE 1800 ARLINGTON , VA 22209-9889										
TITLE Method of purging wafer receiving jig, wafer transfer device, and method of manufacturing semiconductor device										
							All Fees			
RECEIVED	No	S: Authority has been gi to charge/cro for following	edit DEP	aper OSIT ACCOU	☐ 1.16 Fees (Filing) ☐ 1.17 Fees (Processing Ext. of time)					
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